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#7/5-1-02

## **PATENT**

# IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Koh et al.

Group Art Unit: 2811

Serial No.: 09/891,905

Examiner: Thien F. Tran

Filed: June 26, 2001

For: METHODS OF FORMING INTEGRATED CIRCUITS USING MASKS TO

PROVIDE ION IMPLANTATION SHIELDING TO PORTIONS OF A SUBSTRATE ADJACENT TO AN ISOLATION REGION THEREIN

April 12, 2002

Commissioner for Patents Washington, DC 20231

# INFORMATION DISCLOSURE STATEMENT PURSUANT TO 37 C.F.R. § 1.97(i)

Sir:

Attached is Form PTO-1449 listing documents cited in an Official Action issued by the Korean Patent Office on 28 January 2002 for the corresponding Korean Application Number 10-2000-0035707. A copy of the documents, including the Official Action, is enclosed. It is requested that these documents be placed in the file in accordance with the provisions of 37 C.F.R. § 1.97(i) and Section 609 of the MPEP.

The Commissioner is hereby authorized to charge any additional fee, which may be required, or credit any refund, to our Deposit Account No. 50-0220.

Respectfully submitted,

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20792

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#### **CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, Washington, DC 20231, on April 12, 2002.

Audra Wooten

Date of Signature: April 12, 2002